Reply to OA dated August 8, 2006

AMENDMENTS TO THE CLAIMS:

Please cancel claims 5, 10 and 11 without prejudice or disclaimer, and amend claims 1, 3 and

4, as follows. This listing of claims will replace all prior versions, and listings, of claims in the

application:

Listing of Claims:

Claim 1 (Currently Amended): A substrate for an electronic-optical united device used for

fabricating being a component of an electronic-optical united device mixedly incorporating an

electronic device such as an LSI and an optical device such as an LED and a laser diode, comprising

a monocrystalline silicon substrate being an SOI substrate including:

one area having at least one layer, wherein none of the layers of said one area is

metamorphosed formed with the electronic device; and

another area formed with the electronic device, comprising:

a layer of silicon carbide metamorphosed by locally carbonizing the corresponding area in

the monocrystalline silicon SOI substrate; and

a layer of monocrystalline gallium nitride grown on said layer of silicon carbide.

Claim 2 (Canceled).

-2-

U.S. Patent Application Serial No. 10/699,832 Amendment filed December 8, 2006 Reply to OA dated August 8, 2006

Claim 3 (Currently Amended): A substrate for an electronic-optical united device according to claim 1, said one area further comprising:

a layer of silicon nitride formed on the monocrystalline silicon SOI substrate.

Claim 4 (Currently Amended): A substrate for an electronic-optical united device according to claim 1, said one area further comprising:

a layer of silicon oxide formed on the monocrystalline silicon SOI substrate.

Claims 5-11 (Canceled).

Claim 12 (Previously Presented): A substrate for an electronic-optical united device according to claim 3, said one area further comprising:

a layer of polycrystalline gallium nitride grown on the layer of silicon nitride.

Claim 13 (Previously Presented): A substrate for an electronic-optical united device according to claim 4, said one area further comprising:

a layer of polycrystalline gallium nitride grown on the layer of silicon oxide.